



**INFORMATION DISCLOSURE  
STATEMENT BY APPLICANT**

**Application Number** 10/716,770

**Filing Date** **November 19, 2003**

**First Named Inventor**

Group Art Unit 2881

**Examiner Name**

~~Fernandez, Katimah~~ *Nicole Wells*

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Attorney Docket **UBAT1530**

## U.S. PATENT DOCUMENTS

O I P INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Application Number	10/716,770
				Filing Date	November 19, 2003
				First Named Inventor	Guillorn
				Group Art Unit	2881
				Examiner Name	Fernandez, Kalimah N. / Ta Wells
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Examiner Signature	<i>Julita Wells</i>	Date Considered <i>March 13, 2006</i>

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				Group Art Unit	2881
				Examiner Name	Fernandez, Kalimah- <i>Nikita Wells</i>
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Examiner Signature	<i>Nikita Wells</i>	Date Considered March 13, 2006